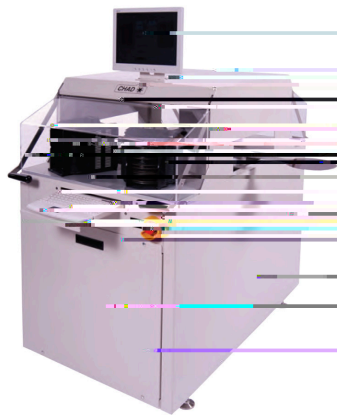


WAFERMATE200™

ROBOTIC WAFER HANDLING

HIGH PERFORMANCE 0.15µm & 0.18µm



SPECS

Machine Footprint	609mm x 1244 mm
Wafer Alignment	to ± .05°
Wafer Placement	±100µm
Clean Room Classification	Up to ISO Class 4 (Optional)
Wafer Interface Options	<ul style="list-style-type: none"> - SMEMA - Serial - SECS/GEM - Wafer Conveyor
Loadport Positions Available	Up to 4 x 200mm Cassettes
MTBF	